

Graduate RA Openings – MEMS and microfabrication

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We currently have multiple graduate student openings for experimental research on microelectromechanical systems (MEMS).

The planned research project will focus on developing ultra-stable MEMS resonators for timing applications. The project will give the candidate experience with developing a new fabrication process, MEMS system design, and on the integration of ASICs with MEMS devices.

Ideal applicants will have the following –

1. A strong interest and background in MEMS and microfabrication. This can be through hands on research experience or through relevant coursework. Practical experience with microfabrication and working in a cleanroom (e.g. at the level of ME487 or ECE444 at UIUC) would be very valuable.
2. Familiarity with frequency domain analysis and elementary signal processing is strongly recommended (e.g. at the level of ME360 at UIUC).
3. Experience with basic circuit design (e.g. using operational amplifiers), and hands on experience with the use of RF/electronic test and measurement (oscilloscopes, network analyzers, lock-in amps) will be desirable.

Interested candidates should contact Prof. Gaurav Bahl with their complete CV, accompanied by a short paragraph highlighting practical experience relevant to this position.